

Notification of Abstract Acceptance _NNT 2011

First Name	Last Name	Organization	Country	Abstract Title	Corresponding Author
Presentation Type: Oral					
Henry J. H.	CHEN	National Chi Nan University	Taiwan	Fabrication of SONOS Type Poly-Si TFTs Memory with 3-D Fin-like Channels Using Nano Imprint Technology	Henry J. H. Chen
Iris	BERGMAIR	PROFACTOR GmbH	Austria	Optimizing optical properties of negative index materials fabricated by NIL	Iris Bergmair
Shinill	KANG	Yonsei University	Korea	Fabrication of magnetic nanotracks in the (CoOx/Pd)10 multilayer using UV-nanoimprinting lithography and low-energy ion irradiation	Shinill Kang
Joonam	KIM	Tokyo Institute of Technology	Japan	Leakage current property of the PZT films improved by thermal press treatment	Tatsuya Shimoda
Youngtae	CHO	Samsung electronics	Korea	Application of nano imprint process to the solar cell fabrication : efficiency enhancement by anti reflection and light scattering	Youngtae Cho
Vaida	AUZELYTE	École Polytechnique Fédérale de Lausanne	Switzerland	Direct nanoimprint of plasmonic nanostructures on gold- parylene layer	Vaida Auzelyte
Keiko	TAWA	AIST	Japan	700fM-Tumor-Marker Detection with bispecific antibody immobilized on the ZnO-coated Plasmonic Chip	Keiko Tawa
Hong Yee	LOW	Institute of Materials Research and	Singapore	Repairable Micro and Nano-structures	Hong Yee Low
Sun	CHOI	UC Berkeley	United States	A Zero-Power, High-Throughput Micro, Nanoparticle Printing via Gravity-Driven Formation of Picoliter-Scale Droplets	Sun Choi
Jihye	Lee	KIMM	Korea	Fabrication of planar nanogap field effect transistor using nanoimprint lithography and its application for sensing biomolecules	Jihye Lee
Iris	BERGMAIR	PROFACTOR GmbH	Austria	Fabrication of μm and nm graphene structures using UV-NIL	Iris Bergmair
Khalid	DHIMA	university of Wuppertal	Germany	Reversed order hybrid lithography of T-NIL and UVL	Khalid Dhima
Ayoung	LEE	Seoul National University	Korea	The effect of flow-induced aggregation on the stability of ZnO nanodispersions during ink-jet printing process	Kyung Hyun Ahn
Naoki	NISHIKURA	Osaka Prefecture University	Japan	Nanoimprint lithography by dispersed molecular weights resist	Y. Hirai
Kenta	SUZUKI	National Institute of Advanced Industrial	Japan	Evaluation of Actual Line Width of Sub-100nm UV-NIL Patterns by Extremely Shallow Si Etching	Hiroshi Hiroshima
Daesuk	KIM	Chonbuk National University	Korea	3D micro-nanoscope using snapshot imaging polarimetry	Daesuk Kim
Akira	HORIBA	Osaka. Prefecture University	Japan	The Measurement of Viscosity of Ultrathin Resists Used in Nanoimprint Lithography	Yoshihiko Hirai
Hiroshi	HIROSHIMA A	National Institute of Advanced Industrial	Japan	For Understanding of Filling Process in UV Nanoimprint Using a Spin-coat UV Curable Resin Film	Hiroshi Hiroshima
Kentaro	ISHIBASHI	WASEDA University / Toshiba machine co.	Japan	Optimized Step and Repeat UV Nanoimprint process for Large Scale Nano Pattern fabrication	Kentaro Ishibashi
Po Jin	KIM	Pusan National University	Korea	Simulation of Demolding Process for Throughput Improvement of Roll to Roll UV Imprint Lithography	Myung Yung Jeong
Seunghwa	YANG	Seoul National University	Korea	Characterization of thermal NIL process with mechanically preloaded semi-crystalline resist by molecular dynamics	Maenghyo Cho
Sanghyeok	KIM	Korea Advanced Institute of Science	Korea	Direct micro/nano-printing by two-step transfer process of metal nano-inks	Inkyu park
Jong-Ning	AOH	National Chung Cheng University	Taiwan	The fabrication of nano-scale gratings on metal/PMMA stack layer using direct nanoimprint	Jong-Ning Aoh
Hayden	TAYLOR	Simprint Nanotechnologies Ltd	United Kingdom	Fast simulation of nanoimprint lithography: modelling capillary pressures during resist deformation	Hayden Taylor
Thomas	BU	Institut for Mikro- og Nanoteknologi	Denmark	Investigation of Cross-talk in Nanoimprint Lithography	Thomas Bu
Jian	HE	GeSiM – Gesellschaft fuer Silizium-	Germany	Deformations of soft imprint templates in the Nanoimprint Lithography	Jian He
Erwin	MEINDERS	TNO	Netherlands	Nanoimprint lithography as enabling patterning technology for embedded metal grid structures used in large-area printed electronics	Dr. Erwin Meinders
Hiroyuki	SUYAMA	PULSTEC INDUSTRIAL CO.,LTD.	Japan	Fabrication of Seamless Roll mold for nano-imprint process	Hiroyuki Suyama
Jarrett	DUMOND	Institute of Materials Research & Engineerin	Singapore	Interfacial and Process Considerations in UV Roll-to-Roll Nanoimprinting at 50 nm Resolution: Eliminating Legacy Coatings and Improving	Jarrett Dumond
Yung-Chun	Lee	National Cheng Kung University	Taiwan	Seamless Roller Molds for Large-Area Fabrication of Optical Films with Ball-Shaped Micro-Lens Array	Yung-Chun Lee
Masayuki	ABE	Asahi Kasei Engineering Co., LTD.	Japan	Fabrication of Large Area Seamless Roller Mold using Fast EB Lithography (REBL) for R2R Process	Masayuki Abe
Makoto	OKADA	Univ. of Hyogo	Japan	Characteristics of thin polydimethylsiloxane layer formed by using silane coupling agent	Makoto Okada
Andre	MAYER	University of Wuppertal	Germany	Low temperature thermal imprint via frequency assistance	Andre Mayer
Atsushi	YOKOO	NTT Basic Research Laboratories	Japan	Nanoelectrode lithography - Chemical Nanoimprint with electrochemical reaction -	Atsushi Yokoo
Si-Hyeong	CHO	Hanyang University	Korea	Fabrication of template with various Si micro/nano tip array based on Reactive ion etching	Jin-Goo Park

Presentation Type: Poster					
Alireza	MOJAB	University of Tehran	Iran	A Numerical Study of Acidic Texterization of Multicrystalline Silicon Solar Cells	Morteza Fathipour
Yung Kang	SHEN	Taipei Medical University	Taiwan	Analysis on nano-structured anti-transmittance surface using anodic aluminum oxide template by nanoimprint processing	Yung-Kang Shen
Byung-Kyu	LEE	Samsung Electronics (SAIT)	Korea	Quartz replica template & process for 30nm CMOS	Byung-Kyu Lee
Nan	LU	Jilin University	China	Fabrication of metal arrays with nanoimprint lithography	Nan Lu
Jheng yuan	CHEN	National Chiao Tung University	Taiwan	Biomimetic nanostructured broadband antireflection coating and its application on crystalline solar cells	K.W. Sun
Elisabeth	LAUSECKER	University of Linz	Austria	Ordered SiGe island arrays on pit-patterned Si(001) substrates fabricated by UV-NIL: towards sub-100 nm period and photonic applications	Elisabeth Lausecker
Hyunduck	CHO	Seoul National University	Korea	Full-color patterning of colloidal quantum dots on an organic hole transport layer using the transplanting technique	Changhee Lee
Nikos	KEHAGIAS	Catalan Institute of nanotechnology	Spain	Combination of lithography techniques for the fabrication of sub 100 nm three dimensional structures	Nikos Kehagias
Kyoung Je	CHA	POSTECH	Korea	Development of Nanoengineered Plastic Surfaces and their application to osteoblast differentiation	Dong Sung Kim
Meera	THIYAGARAJAN	Vivekanandha College of Engineering for	India	Energy efficiency of nano magnetic particles	Mrs.Meera Thiyagarajan
Satoshi	SHIMATANI	Tokyo Ohka Kogyo co., LTD	Japan	Fabrication of photonic crystal with nanoimprint lithography	Noriaki Taneichi
Trinh	BUI	Japan Science and Technology Agency	Japan	Nano-sized Pt Lines and Spaces Patterned by Nanoimprint Lithography and Physical Dry-etching Method	Bui Nguyen Quoc Trinh
Duckjong	KIM	Korea Institute of Machinery and	Korea	Heat Spreading in Transparent Carbon Nanotube Films	Duckjong Kim
Makoto	OKADA	Univ. of Hyogo	Japan	Double patterning by UV-Nanoimprinting	Makoto Okada
Alireza	MOJAB	University of Tehran	Iran	The Effect of Lithography Misalignment on the Performance of LDMOS Transistors	Morteza Fathipour
Chung-Soo	KIM	Seoul National University	Korea	Hybrid Nanoscale Manufacturing System using Focused Ion Beam and Nanoparticle Deposition Systems	Sung-Hoon Ahn
Akira	HORIBA	Osaka Prefecture University	Japan	Shrinkage Pattern Correction (SPC) in Nanoimprint Lithography	Yoshihiko Hirai
Ryosuke	SUZUKI	Osaka Prefecture University	Japan	Characterization of resist properties for UV nanoimprint	Yoshihiko Hirai
Kohei	TOMOHIRO	Osaka Prefecture University	Japan	Defect inspection on mold releasing process for high aspect ratio pattern transfer	Yoshihiko Hirai
Shokouh	SHAHBAZI	Islamic Azad University	Iran	The Effect of Implanting p-top and n-top Layers on the Performance of LDMOS Transistor with Nanometer channel	Fathipour (Dr)
Ryosuke	SUZUKI	Osaka Prefecture University	Japan	Simulation analysis of the resist filling process for UV nanoimprint in condensable gas	Yoshihiko Hirai
Deokkyun	YOON	Korea Institute of Machinery and	Korea	Quality of Printed Features in Multilayer Printing	Deokkyun Yoon
Arghya	BANERJEE	Yeungnam University	Korea	Optical properties of nanocrystalline ZnO thin films deposited on plastic substrate via low-temperature sputtering process for roll-to-roll	Arghya Narayan Banerjee
Kiju	SOHN	Seoul national university	Korea	Numerical Simulation of Roll-to-Roll Hot Embossing on Polycarbonate Films	Woo-il Lee
Yung-Chun	Lee	National Cheng Kung University	Taiwan	Sub-Micrometer Pyramid-Shaped 3D Structures Fabricated by Metal Contact Printing Lithography	Yung-Chun Lee
Chien-Li	WU	National Tsing Hua University	Taiwan	Seed Layer Properties of Electroless Nickel (EN) Plating for Nanoimprint Stamp Fabrication	Cheng-Kuo Sung
Sen-Yeu	YANG	National Taiwan University	Taiwan	Fabrication of a microlens array on a PMMA substrate by A gasbag-roller-assisted UV imprinting technique	Sen-Yeu Yang, Cheng-Huan Yang, Chia-Lin
Jian	HE	GeSiM – Gesellschaft fuer Silizium-	Germany	µCP 4.0 – A new GeSiM NIL/µCP Platform for Research and Fabrication in Biotechnology and Material Science	Jian He
Si	WANG	university of wuppertal	Germany	Preparation of random stamps for thermal nanoimprint	Si wang
Junhyuk	CHOI	Korea Institute of machinery & materials	Korea	Optical Properties affected by Sidewall Configuration of Imprinted Metal Pattern Arrays	Junhyuk choi
Byungjin	CHO	gwangju Institute of science and	Korea	Unipolar organic resistive memory devices scaled down by a direct metal-transfer method	Takhee Lee
Alexander	CHRISTIAN SEN	Technical University of Denmark	Denmark	Large area color effects in polymer replica of black silicon	Alexander bruun Christiansen
Seunghyun	RA	Samsung Electro-Mechanics	Korea	Applications of Moth-eye Type Anti-Reflection Effect Using Imprint Technology	Seunghyun Ra
Foad	YAZDI	Islamic Azad University of tehran central	Iran	The effect of nano layer on single junction In0.2Ga0.8N solar cell	Morteza Fathipour
Foad	YAZDI	Islamic Azad University of tehran central	Iran	The impact of window and back surface field nano layers on the single junction GaAs based solar cell	Morteza Fathipour
Huisu	JEONG	Gwangju Institute of Science and	Korea	Crossbar-type High Sensitivity Ultraviolet Photodetector Array based on One Hole – One Nanorod Configuration via Nanoimprint Lithography	Gun Young Jung
Hak-Rin	KIM	Kyungpook National University	Korea	Spontaneously Formed Dual-groove Structure Fabrication for Liquid Crystal Alignment	Hak-Rin Kim
Chiyong	LEE	Kookmin university	Korea	Fabrication of resistive switching random access memory (ReRAM) using nano-imprinting process	Jaegab Lee
Sung Mook	CHUNG	ETRI	Korea	Fabrication of ITO:Ta thin film transistors by co-sputtering	Sung Mook Chung
Sang Chul	OH	Korea university	Korea	Fabrication of metallic nano pattern on metal plate using direct embossing technique	Heon Lee

Joong Yeon	CHO	Korea University	Korea	Enhancement of photon extraction efficiency of GaN-based LED using high refractive-index photonic crystal structures	Heon Lee
Won Seok	LEE	KAIST	Korea	Thermocompression transfer printing process for improved bonding between nanowires and metal electrodes	Jihye lee
Sangmin	AN	Seoul National University	Korea	Direct Patterning of PDMS using the Pulled Pipette based on the QTF-AFM System	Sangmin An
Yongsuk	OH	KAIST	North Korea	Quantum Dot Arrays Patterned By Direct Nanoimprinting	Hyung Jin Sung
Sohee	JEON	Korea Institute of Machinery and	Korea	Corrugated organic light emitting diodes using UV imprinted nanostructures for enhanced light extraction	Sohee Jeon
Yoonyoung	CHOI	KAIST	Korea	Ferroelectric nanodot formation in spin coated poly (vinylidene fluoride-trifluoroethylene) films	Jongin Hong and Kwangsoo No
Sang Moon	KIM	Seoul National University	Korea	Free Sliding-droplet on Lotus-Leaf-like Surface for Rapid PCR	Kahp-Yang Suh
Won-Gyu	BAE	Seoul National University	Korea	Fabrication of hierarchical structure by wire EDM for metallic superhydrophobic surface	Kahp Y. Suh
Seongmin	KANG	Seoul National University	Korea	Bio-inspired Polymeric Omniphobic Surfaces	Kahp Y. Suh
Chikara	YASUI	Kansai University	Japan	Sensitive Fluorescence Microscopic Observation of Neurons Cultured on a Plasmonic Chip	Keiko tawa
SungHo	LEE	Korea Institute of Industrial Technology	Korea	Study on drag force of bubble for fluidic self-assembly	SungHo Lee
Sakshin	BUNTHAWIN	Prince of Songkla University	Thailand	Dielectrophoresis of Arsenic Pretreated Unicellular Green Alga in a Traveling Electric Fields Analyzed Using the RC Model	Assist. Prof. Dr. sakshin Bunthawin
Sakshin	BUNTHAWIN	Prince of Songkla University	Thailand	Micro-Electrode Development for Separation of Cell Suspension in Travelling Waves	Assist. Prof. Dr. sakshin Bunthawin
Sarah	KIM	Korea Institute of Machinery and	Korea	Self-assembly of block copolymer via direct nanoimprint lithography	Jun-Ho Jeong
Andreas	RANK	PROFACTOR GmbH	Austria	Nanometer Size Protein Patterning using Reversal micro-CP	Andreas Rank
Lee	SEONG-HWAN	Korea University	Korea	Fabrication of High-Transparent Self-cleaning Flexible Polymer Films using Hot-embossing and Nanoimprint Lithography	Heon Lee
Mun Ho	KIM	Korea Research Institute of chemical	Korea	Fabrication of Periodically Arrayed Nanostructures Using Poly(dimethylsiloxane) Replica Molds Based on Three-Dimensional	Mun Ho Kim
Timothy	KEHOE	Catalan Institute of Nanotechnology	Spain	Swellable hydrogels imprinted for optical sensor structures	Timothy Kehoe
JunHee	LEE	Korea Institute of Machinery & Materials	Korea	Characterization of Blended Polymer Scaffold using 3D Plotting System	JunHee Lee
KIYOUNG	KIM	KITECH	Korea	Development of Optical Material for Improvement of Solar Energy Absorption	Ki Young Kim
Robert	FADER	Fraunhofer IISB	Germany	UV-enhanced Substrate Conformal Imprint Lithography Using an Epoxy Based Polymer	Robert Fader
Won-Gyu	BAE	Seoul National University	Korea	Fabrication of size-controllable nano structures by thermally induced shape-memory lithography	Kahp Y. Suh
Yohei	SAWADA	Graduate school of science, Univ. of	Japan	Evaluation of polymerization degrees of UV-nanoimprinting patterns fabricated in PFP gas ambient	Yohei Sawada
Kazuhisa	KUMAZAWA	Nippon Soda Co., Ltd.	Japan	Surface Self-Vitrification Coating: The Novel Organic/Inorganic Hybrid Film for Nanoimprint Process	Kazuhisa KUMAZAWA
Kwon-Yong	SHIN	KITECH	Korea	Effects of Solvent Evaporating Rate and Thermal Treatment Methods on Shapes of Inkjet Printed Droplets	Sang-Ho Lee
Yuji	KANG	University of hyogo	Japan	Characteristics of liquid-phase HSQ resin effects on the room-temperature nanoimprinting	Yuji Kang
Mika	CHINEN	material science	Japan	Evaluation of interaction between UV-nanoimprint resin and antisticking layer by dynamic contact angle measurement	Mika Chinen
Hakan	ATASOY	micro resist Technology GmbH	Germany	Development of Ink-Jet Dispensable UV-NIL Resists with Advanced Release Properties	Hakan Atasoy
Michael	HORNUNG	Suss MicroTec Lithography GmbH	Germany	Temperature Assisted UV-Nanoimprint Lithography using Epoxy Based Resist	Michael Hornung
Olivier	LORRET	PROFACTOR GmbH	Austria	Multi-functionalized Polyhedral Oligomeric Silsesquioxanes: Promising Materials for UV-Nanoimprint Lithography	Olivier Lorret
Jong-Woong	KIM	Korea Electronics Technology Institute	Korea	Top-down fabrication of SiC nanoparticles for applications in Printed Electronics	Jong-Woong Kim
Martin	MESSERSCHMIDT	micro resist technology GmbH	Germany	Fabrication of High-Aspect-Ratio Patterns Applying a New Thermal Si-containing Nanoimprint Resist	Martin Messerschmidt
Cheol Min	YUN	tohoku university	Japan	Gas permeability of nanoimprinted PDMS-grafted polyimide membranes	Masaru Nakagawa
Masaru	NAKAGAWA	Tohoku University	Japan	Fluorinated 1-octanol working as an adhesive-force-reducing reagent for a UV-curable resin in UV nanoimprinting	Masaru Nakagawa
Hyung-sub	LIM	UST	Korea	Nanopatterning of Metal Oxide with High Refractive Index by Direct UV Nanoimprint Lithography	Jun-Ho Jeong
Fan	YANG	Harbin Institute of Technology	China	Temperature effect of Vapor-phase self-assembled monolayer deposition for anti-sticking layers	Peng Jin
Seungmin	HYUN	Korea Institute of Machinery and	Korea	Mechanical behavior in nano-scale thick Al films at elevated temperature	Seungmin Hyun
Kwang-Seop	KIM	Korea Institute of Machinery & Materials	Korea	Measurement of interfacial adhesion energy between graphene sheets and UV-curable polymer	Hak-Joo Lee
Tomoki	NISHINO	Osaka Prefecture University	Japan	Study on kinetics of de-molding force process in UV nanoimprint	Tomoki Nishino
Seungmin	HYUN	Korea Institute of Machinery and	Korea	Mechanical behavior of silicon nitride membrane	Seungmin Hyun
Seung Hoon	NAHM	Korea Research Institute of Standards	Korea	The spun carbon nanotubes print on transparent flexible films	Seung Hoon Nahm

Sang Chul	LIM	IIT Convergence and Components &	Korea	Low-temperature fabrication of the ZnO thin film transistor by inkjet-printing methods	Sang Chul Lim
Won Seok	CHANG	Korea Institute of Machinery and	Korea	Synthesis of Free-Standing Carbon Nanofibers Using Nanoimprint Pattern	Won Seok Chang
Ali	HAGHSHEEN AS	University of tehran	Iran	Dependence of Self-heating Effects on Passivation Layer in AlGaIn/GaN HEMT Devices	Morteza fathipour
Ali	HAGHSHEEN AS	University of tehran	Iran	Investigation of self-heating effects in included field plates structures in AlGaIn/GaN HEMT devices	Morteza Fathipour
Duckjong	KIM	Korea Institute of Machinery and	Korea	Effect of Spray Process Conditions on Uniformity of Carbon Nanotube Thin Films	Duckjong Kim
So Hee	KIM	Pusan National University	Korea	Optimization of the Multi-functional Nanostructure for Nanoimprinting	Myung Yung Jeong
Kosei	ARAKI	Osaka Prefecture University	Japan	Molecular Simulation of Polymer Filling Process in Nanoimprint Lithography for Bi-Layered Resist	Yoshihiko Hirai
Qing	WANG	National Institute of Advanced Industrial	Japan	Impact of air bubble entrapment in a capacity-equalized mold on UV nanoimprint residual layers	Qing Wang
Junji	SAKAMOTO	osaka prefecture university	Japan	Impact of PMMA Molecular Weight on High Aspect Nano Pattern Fabrication by Thermal Nano-Imprint Lithography	Hiroaki Kawata
Junji	SAKAMOTO	osaka prefecture university	Japan	Pattern Size Variations by Residual Layer Etching for PMMA and PS Nano Patterns Fabricated by T-NIL	Hiroaki kawata
Yoon Jae	MOON	Hanyang University(Kitech)	Korea	Effect of Substrate Treatment on Inkjet-Printed Line of Silver Nanoparticle Ink	Jun Young Hwang
Fuh-Yu	CHANG	Nat taiwan uni of sci and tech	Taiwan	PDMS Mold Treatment by Atmospheric Plasma for Micro Contact Printing with Conductive Polymers	Fuh-Yu Chang
Han-Byeol	JO	KOREA Univ.	Korea	Direct fabrication of functional nano-structures by UV nanoimprint using ZnO nano particle-dispersed resin	Heon lee
Junhyuk	CHOI	Korea Institute of machinery & materials	Korea	Roll Nanoimprint with the Stitched Large Template	Junhyuk Choi
Tapio	MAKELA	VTT Microsystems and Nanoelectronics	Finland	PILOT SCALE ROLL TO ROLL NANOIMPRINT PROCESS FOR BACKLIGHT DEVICES	Tapio Makela
Jae Bon	KOO	Electronics and Telecommunications	Korea	Organic Thin Film Transistors with Offset-Printed Ag Electrodes	Jae Bon Koo
Jong su	YU	Korea Institute of Machinery & Materials	Korea	Fabrication of Transparent Conductive CNT Film using Thermal Roll Imprinted Ag Metal Grid Patterns	Jeongdai Jo
Sang-Uk	CHO	pusan national university	Korea	Fabrication of Polymeric PLC Devices by Roll-to-Roll Imprint	Myung Yung Jeong
SATORU	OZAWA	mitsubishi rayon CO.,LTD.	Japan	A study on the improvement of mold life-time in UV nanoimprint	Yuusuke Nakai, Tetsuya Jigami, Shigeo
Eunsoo	HWANG	Samsung Electronics	Korea	A Wrapped Pattern Roll Mold and Its Overlay Accuracy Control in R2R Imprint Lithography on Flexible Film	Eunsoo Hwang
Bongkyun	JANG	Korea Institute of Machinery and	Korea	A study on contact mechanics of continuous transfer process of thin film with a large area	Jae-hyun Kim
Yung-Chun	LEE	national Cheng Kung University	Taiwan	Sub-Micrometer Pyramid-Shaped 3D Structures Fabricated by Metal Contact Printing Lithography	Yung-Chun Lee
Jieun	KO	Seoul National University	Korea	Low Cost Fabrication of Transparent Hard Replica Molds Appropriate for Imprinting Lithography	Youn Sang Kim
Hyung Sik	UM	Seoul National Univ	Korea	Fabrication of Temperature Dependent Gradient Patterns and Height dependent Uniform Pattern Using Reflow Process	Hyung Sik Um
Beum Jin	PARK	Kwangwoon University	Korea	Fabrication of snowman-pattern of silica particle using microcontact printing with pressure gradient	Younghun Kim
Sone	SHIN-ICHIRO	soka university	Japan	Research on cleaning of thermal resin Nano-Imprint Lithography Template with hydrostatic pressure	A. Shimizu
Yuta	KAJIWARA	Soka University	Japan	Remove the Photo-Curable Resin on the Nanoimprint Lithography Template with Hydrostatic Pressure	A. Shimizu
AYeong	CHA	pusan national university	Korea	Fabrication of Ni Stamp with 3D Nano-paraboloid Shape for High-efficiency Solar Cell	Myung Yung Jeong
Jaehyung	HAN	Electronics and Telecommunications	Korea	Fabrication of Moth-eye Antireflection Nanostructures by Anodized Aluminum Oxide Membranes	Choon-Gi Choi
Gerald	KREINDL	EV Group	Austria	Hybrid Tri-Layer Stamps for Step and Repeat Imprint Lithography	Gerald Kreindl
HyungJun	LIM	Korea Institute of Machinery & Materials	Korea	Modeling and Analysis of Overlay Errors in Large-Area Nanoimprint Lithography	HyungJun Lim
Bong Kuk	LEE	Electronics & Telecommunications	Korea	High Performance Nonstick Replicas for High-Resolution Nanoimprint Lithography	Lee-Mi Do
Tomi	HAATAINEN	VTT	Finland	Nanoimprint fabrication process for hybrid 3D stamps	T. Haatainen
Siyoul	JANG	Kookmin Univ.	Korea	Resin Layer Thickness Variations in UV Imprinting Process with the Elastic Deformation of Mold	Siyoul Jang
Sung-Won	YOUN	National Institute of AIST	Japan	A Study on Grayscale Laser Beam Lithography on Nano Patterned Quartz Substrate	S. W. Youn
Jihye	LEE	Korea Institue of Machinery and	Korea	Fabrication of a multilayered 3D quartz template for nanoimprint lithography using quartz-to-quartz direct bonding	Jihyelee@kimm.re.kr
Seok-min	KIM	Chung-Ang University	Korea	Fabrication of vitreous carbon nanostamp for glass thermal nanoimprinting	Seok-min Kim
Cho-Yun	YANG	National Tsing Hua University	Taiwan	Applying APCVD to the Anti-adhesion Treatment of Nanoimprint Stamp	Cheng-Kuo Sung
Jun-Ho	JEONG	Korea Institue of Machinery and	Korea	Fabrication of Large Area Nano-Structured Stamp by Using Stitch Nanoimprint Lithography	Jun-Ho Jeong